



DOCKET 1449 (Modified)

**Information Disclosure
Statement By Applicant**

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Attorney Docket No:	U.S.
LAM2P422	10/608,871
Applicant:	
John M. de Larios	
Filing Date:	Group:
June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
A1	3,037,887	06/5/1962	Brenner et al.	134	22	
B1	3,212,762	10/19/1965	Carroll et al.	261	124	
C1	3,436,262	04/1/1969	Crowe et al.	134	10	
D1	3,617,095	11/02/1971	Lissant	406	197	
E1						
F1	4,085,059	04/18/1978	Smith et al.	134	26	
G1	4,133,773	01/9/1979	Simmons	261	21	
H1	4,156,619	05/29/1979	Griesshammer	134	2	
I1						

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
J1	DE-40-38-587	06/11/1992	DE	Fig 1-5	N/A			X
K1	EP-0827188	03/04/1998	EP	G03F7	42		X	
L1	EP-0905746	03/31/1999	EP	H01L 21	00		X	
M1	EP-0989600	03/29/2000	EP	H01L21	465		X	
N1	JP-2001-064688	03/13/2001	JP	H01L21	304		X	

Other Documents

Examiner		
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
O1		AUBERT, JM et al.; "Aqueous foams"; Scientific America; 1986, 74-82, 254
P1		KITTLE, et al.; "Semiconductor Wafer Cleaning and Drying Using a Foam Medium"; <http://www.aquafoam.com/papers;SCI0202.pdf>; Sematech Novel Wafer Cleans Working Group Meeting, Internet Presetation; 11/13/2001
Examiner		Date Considered

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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A2	4,238,244	12/9/1980	Banks	134	22
	B2	4,781,764	11/1/1988	Leenaars	134	34
	C2	4,817,652	04/4/1989	Liu et al	134	102
	D2					
	E2	4,849,027	07/18/1989	Simmons	134	22
	F2	4,911,761	03/27/1990	McConnell et al.	134	11
	G2	4,962,776	10/16/1990	Liu et al.	134	11
	H2	5,000,795	03/19/1991	Chung et al.	134	37
	I2	5,048,549	09/17/1991	Hethcoat	134	122R

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J2	JP-02-309638-A	12/25/1990	JP	N/A	N/A	X	
	K2	JP-06-177101	06/24/1994	JP	H01L21	304	X	
	L2	JP-07-006993	01/10/1995	JP	H01L21	304	X	
	M2	EP-11-334874	12/07/1999	EP	B65G	49/07	X	
	N2							

Other Documents

Examiner		
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O2	
	P2	LESTER; "Advanced Wafer-Cleaning Evolution"; < http://www.aquafoam.com/papers/SCI0202.pdf >; Semiconductor International, 25, #2; 2/1/2002
Examiner	Date Considered	

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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A3	5,102,777	04/07/1992	Lin et al.	430	331
	B3	5,105,556	04/21/1992	Kurokawa et al.	34	12
	C3	5,113,597	05/19/1992	Sylla	34	22
	D3	5,175,124	12/29/1992	Winebarger	437	180
	E3	5,181,985	01/26/1993	Lampert et al.	156	635
	F3	5,226,969	07/13/1992	Watanabe et al.	134	7
	G3	5,242,669	09/7/1993	Flor	423	465
	H3					
	I 3	5,288,332	02/22/1994	Pustilnik et al.	134	27

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J3							
	K3							
	L3							
	M3	JP-2002-66475	03/01/2002	JP	E03C	1/12	X	
	N3	JP-2005-194294	07/21/2005	JP	H01L21	304	X	

Other Documents

Examiner		
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O3	
	P3	
Examiner	Date Considered	

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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A4	5,306,350	04/26/1994	Hoy et al.	134	22.14
	B4	5,336,371	08/09/1994	Chung et al.	156	659.1
	C4	5,415,191	05/16/1995	Mashimo et al.	134	102.1
	D4	5,417,768	05/23/1995	Smith et al.	134	10
	E4					
	F4	5,472,502	12/05/1995	Batchelder	118	52
	G4	5,494,526	02/27/1996	Paranjpe	134	1
	H4	5,498,293	03/12/1996	Ilardi et al.	134	3
	I4	5,656,097	08/12/1997	Olesen et al.	134	1

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J4	JP-5-15857	1/5/1993	JP	B08B	1/04	X	
	K4	JP-53-076559	7/7/1978	JP	B08B	3/00	X	
	L4	JP-56-084618	7/10/1981	JP	B01D	53/34	X	
	M4	JP-56-084619	7/10/1981	JP	B01D	53/34	X	
	N4	JP-59-24849	2/08/1984	JP	205	704	X	

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O4	KITTLE, et al.; "Photoreisist Removal Using Aqueous Foam"; Internet; http://www.aquafoam.com/paper/SCCPresentation.pdf
	P4	KITTLE, et al.; "Aqueous Foam Drying and Cleaning of Semiconductor Wafers"; Internet; http://www.aquafoam.com/paper/SCCPresentation.pdf
	Q4	KITTLE, et al.; "Foam Wafer Cleaning - Experimental Proof of Concept"; Internet; http://www.aquafoam.com/paper/Removalall.pdf
	R4	KITTLE, et al.; "Particulate Removal Using a Foam Medium"; Internet; http://www.aquafoam.com/paper/particulate.pdf
	S4	KITTLE, et al. "Removing Particles with a Foam Medium" Internet http://www.aquafoam.com/paper/A2C2foamedium.pdf
Examiner		Date Considered

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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A5	5,660,642	08/26/1997	Brittén	134	30
	B5					
	C5	5,800,626	09/01/1998	Cohen et al.	134	1.3
	D5					
	E5					
	F5	5,904,156	05/18/1999	Advocate, Jr. et al.	134	2
	G5	5,908,509	06/01/1999	Olesen et al.	134	1.3
	H5	5,911,837	06/15/1999	Matthews	134	2
	I5	5,932,493	08/3/1999	Akatsu et al.	438	745

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J5	JP-60-005529	1/12/1985	JP	H01L	21/304	X	
	K5	JP-62-119543	5/30/1987	JP	H01L	21/304		X
	L5	JP-63-077510	4/7/1988	JP	B01D	36/00	X	
	M5							
	N5							

Other Documents

Examiner		
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O5	KITTLE, et al.; "Photoresist Residue Removal Using Aqueous Foam Proof of Concept Experiments"; Internet; http://www.aquafoam.com/paper/Proof-11MB.pdf ; <papers/A2C2photoresist.pdf>; 13-17; 5/1/2002
	P5	LIDE; "Air Composition"; CRC handbook of Chemistry and Physics; 1997;
	Q	
Examiner		Date Considered

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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A6	5,944,581	08/31/1999	Goenka	431	39
	B6	5,944,582	08/31/1999	Talieh	451	41
	C6					
	D6	5,951,779	09/14/1999	Koyanagi et al.	134	2
	E6	5,964,954	10/12/1999	Matsukawa et al.	134	6
	F6	5,964,958	10/12/1999	Ferrell et al.	134	26
	G6	5,968,285	10/19/1999	Ferrell et al.	134	26
	H6					
	I6	6,048,409	04/11/2000	Kanno et al.	134	34

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J6	WO-00/59006	10/5/2000	WIPO	H01L	21/00	X	
	K6	WO-01/12384	2/22/2001	WIPO	B24B	37/00	X	
	L6	WO-02/101795	12/19/2002	WIPO	H01L	21/00	X	
	M6	WO-2000/33980	6/15/2000	WIPO	B08B	3/00	X	
	N6	WO-2005/006424	1/20/2005	WIPO	H01L	21/306	X	

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O6	
	P6	
	P6	
Examiner		Date Considered

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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A7	6,049,996	04/18/2000	Freeman et al.	34	362
	B7	6,081,650	06/27/2000	Lyons et al	386	95
	C7	6,090,217	07/18/2000	Kittle	134	11
	D7	6,092,538	07/25/2000	Arai et al.	134	1.3
	E7	6,152,805	11/28/2000	Takahashi	451	36
	F7	6,158,445	12/12/2000	Olesen et al.	134	1.3
	G7	6,167,583	01/02/2001	Miyashita et al.	15	77
	H7	6,228,563	05/08/2001	Starove et al.	430	327
	I7					

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J7	WO 2005/064647	7/14/2005	WIPO	H01L	21/00	X	
	K7	WO-99/16109	4/1/1999	WIPO	H01L	21/00	X	
	L7	JP 2003-282513	10/03/2003	JP	H01L	21/304	X	
	M7							
	N7							

Other Documents

Examiner		
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	O7	
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	P7	
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A8	6,270,584	08/07/2001	Ferrell et al.	134	26
	B8	6,272,712	08/14/2001	Gockel et al.	15	77
	C8					
	D8	6,286,231	09/11/2001	Bergman et al.	34	410
	E8	6,290,780	09/18/2001	Ravkin	134	6
	F8	6,296,715	10/02/2001	Kittle	134	2
	G8	6,319,801	11/20/2001	Wake et al.	438	585
	H8	6,352,082	03/05/2002	Mohindra et al.	134	25.4
	I8	6,386,956	05/14/2002	Sato et al.	451	57

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J8							
	K8							
	L8							
	M8							
	N8							

Other Documents

Examiner		
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O8	
	P8	
	P8	
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A9					
	B9	6,401,734	06/01/2002	Morita et al.	134	153
	C9	6,423,148	07/23/2002	Aoki	134	3
	D9	6,439,247	08/27/2002	Kittle	134	102.1
	E9	6,457,199	10/01/2002	Frost et al.	15	77
	F9	6,491,043	12/10/2002	Mohindra et al.	134	25.4
	G9					
	H9	6,493,902	12/17/2002	Lin	15	302
	I9	6,513,538	02/04/2003	Chung et al.	134	1.2

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J9							
	K9							
	L9							
	M9							
	N9							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O9	
	P9	
	P9	
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A10	6,51,4921	02/04/2003	Kakizawa	510	175
	B10	6,527,870	03/04/2003	Gotikis	134	6
	C10	6,537,915	03/25/2003	Moore et al.	438	692
	D10	6,532,976	03/18/2003	Huh et al.	134	111
	E10	6,562,726	05/13/2003	Torek et al.	438	745
	F10	6,576,066	06/10/2003	Namatsu	134	30
	G10	6,594,847	07/22/2003	Krusell et al.	15	102
	H10	6,616,772	09/09/2003	de Larios et al.	134	21
	I10	6,733,596	05/11/2005	Mikhaylichenko et al.	134	6

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J10							
	K10							
	L10							
	M10							
	N10							

Other Documents

Examiner		
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	O10	
	P10	
	P10	
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A11	6,787,473	09/07/2004	Andreas	438	692
	B11	6,797,071	09/28/2004	Kittle	134	11
	C11	6,802,911	10/12/2004	Lee et al.	134	28
	D11	6,846,380	01/25/2005	Dickinson et al.	156	354.31
	E11	6,851,435	02/08/2005	Mertens et al.	134	99.1
	F11	6,874,516	04/05/2005	Matsuno et al.	134	148
	G11	6,896,826	05/24/2005	Wojiczak et al.	252	79.1
	H11	6,927,176	08/09/2005	Verhaverbeke et al.	438	745
	I11	6,946,396	09/20/2005	Miyazawa et al.	438	689

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J11							
	K11							
	L11							
	M11							
	N11							

Other Documents

Examiner		
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	O11	
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A12	6,951,042	10/04/2005	Mikhaylichenko et al.	15	77
	B12	7,122,126	10/17/2006	Fuentes	216	689
	C12	2002/0072482	06/13/2002	Sachdev et al.	510	175
	D12					
	E12	2002/0121290	09/05/2002	Tang et al.	134	6
	F12	2002/0185164	12/12/2002	Tetsuka et al.	134	148
	G12	2002/0195121	12/26/2002	Kittle	134	3
	H12	2003/0075204	04/24/2003	de Larios et al.	134	21
	I12	2003/0148903	08/07/2003	Bargaje et al.	510	130

Foreign Patent or Published Foreign Patent Application

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							Yes	No
	J12							
	K12							
	L12							
	M12							
	N12							

Other Documents

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	O12	
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A13	2003/0171239	09/11/2003	Patel et al	510	406
	B13	2003/0226577	12/11/2003	Orll et al.	134	1.3
	C13	2004/0002430	01/01/2004	Verhaverbeke	510	175
	D13	2004/0053808	03/18/2004	Raehse et al.	510	447
	E13	2004/0134515	07/15/2004	Castrucci	134	2
	F13	2004/0159335	08/19/2004	Montierth et al.	134	10
	G13	2004/0163681	08/24/2004	Verhaverbeke	134	28
	H13	2004/0261823	12/30/2004	de Larios	134	31
	I13	2005/0045209	03/03/2005	Tan	134	18

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	J13							
	K13							
	L13							
	M13							
	N13							

Other Documents

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	O13	
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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A14	2005/0132515	06/23/2005	Boyd et al.	15	77
	B14	2005/0133060	06/23/2005	de Larios et al.	134	1.3
	C14	2005/0133061	06/23/2005	de Larios et al.	134	6
	D14	2005/0159322	07/21/2005	Min et al.	510	175
	E14	2005/0176606	08/11/2005	Konno et al.	510	175
	F14	2005/0183740	08/25/2005	Fulton et al.	134	3
	G14	2006/0201267	09/14/2006	Liu	74	89.2
	H14	2006/0283486	12/21/2006	de Larios et al.	134	34
	I14	2006/0285930	12/21/2006	de Larios et al.	406	197

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
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	J14							
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	O14	
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Form 1449 (Modified)		Attorney Docket No:	U.S.
		LAM2P422	10/608,871
Information Disclosure Statement By Applicant		Applicant:	
		John M. de Larios	
15 of 15		Filing Date:	Group:
		June 27, 2003	1746

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A15	2007/0000518	01/04/2007	Korolik et al.	N/A	N/A
	B15	11/639,752	12/15/2006	Boyd et al.	N/A	N/A
	C15	11/743,283	05/02/2007	Freer et al.	N/A	N/A
	D15					
	E15					
	F15					
	G15					
	H15					
	I15					

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